

[10191/1616]

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor(s)

Heribert WEBER et al.

Serial No.

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October 30, 2000

For

MASS FLOW SENSOR HAVING AN

IMPROVED MEMBRANE STABILITY

Examiner

Lilybett Martir

Art Unit

2855

Commissioner for Patents Washington, D.C. 20231

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Signature:

## **AMENDMENT**

SIR:

In response to the Office Action dated July 5, 2002, kindly amend the above-identified application as set forth below.

## IN THE CLAIMS:

Please amend claims 12 and 13 as follows:

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12. (Amended) The mass flow sensor according to claim 9, further comprising:

an oxide layer arranged in the membrane and below the metal layer; and

a recess arranged beneath the nitride layer; wherein the recess does not contain the oxide layer.

13. (Amended) The mass flow sensor according to claim 3, wherein:

the nitride layer is formed by an operation selected from the group consisting of a PECVD operation, a LPCVD operation, and a CVD operation.